IPE			Docket Number (Optional) BUR920040015US1				
(Use several sheets if necessary)			Applicant(s)  Matthew J. Breitwisch, et al.				
			Filing Date 08/05/04		Group Art Unit Unassigned		
		U.S. PATENT	DOCUMENTS				
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		FOREIGN PAT	ENT DOCUMENTS				
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	REP	REF DOCUMENT NUMBER  REF DOCUMENT NUMBER  JP7007075A  OTHER DOC  M.Q. Huda, et al	PRMATION DISCLOSURE CITATION (Use several sheets if necessary)  U.S. PATENT  REF DOCUMENT NUMBER DATE  FOREIGN PATE  JP7007075A 10/1/95  OTHER DOCUMENTS (Including.  M.Q. Huda, et al., "Techniquing using Implantation Mediated	PRMATION DISCLOSURE CITATION (Use several sheets if necessary)  U.S. PATENT DOCUMENTS  REF DOCUMENT NUMBER  FOREIGN PATENT DOCUMENTS  PAPEL DATE  FOREIGN PATENT DOCUMENTS  REF DOCUMENT NUMBER  DATE  COUNTRY  JP7007075A  10/1/95  Japan  OTHER DOCUMENTS (Including Author, Tide, Date, Pertinant Union of Large Education Mediated Selective Etch	DRMATION DISCLOSURE CITATION (Use several sheets if necessary)    Applicant(t)	REF DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS  POREIGN PATENT DOCUMENTS  TOTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)  M.Q. Huda, et al., "Technique for Large Elevation of Source Including Technique for Large Elevation of Source Including Mediated Selective Etching", Electroche	REF DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS TEST  FOREIGN PATENT DOCUMENTS  REF DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS TEST  FOREIGN PATENT DOCUMENTS  REF DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS TEST  FOREIGN PATENT DOCUMENTS  REF DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS TEST  FOREIGN PATENT DOCUMENTS  REF DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS TEST  REF DOCUMENT NUMBER DATE COUNTRY CLASS SUBCLASS TEST  TEST  JP7007075A 10/1/95 Japan TEST  OTHER DOCUMENTS (Including Author, Title, Date, Pentinent Pages, Etc.)  M.O. Huda, et al., "Technique for Large Elevation of Source/Drail Uning Implicatation Mediated Selective Etching", Electrochemical

## IDS - 08/05/2004

## **ELECTRONIC INFORMATION DISCLOSURE STATEMENT**

Electronic Version v18 Stylesheet Version v18.0

Title of Invention

ISOLATED FULLY DEPLETED SILICON-ON-INSULATOR REGIONS BY SELECTIVE ETCH

Application Number:

Confirmation Number:

First Named Applicant: Matthew Breitwisch
Attorney Docket Number: BUR920040015US1

Search string:

( 5306659 or 5324683 or 5391911 or 6020250 or 6492705 ).pn.

## **US Patent Documents**

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
DWO	1	5306659	1994-04-26	Beyer et al		Ð	1
DWO	2	5324683	1994-06-08	Fitch et al			
DWO		5391911	1995-02-21	Beyer et al			1
DWO	4	6020250	2000-02-01	Kenny		}	1
DWO	5	6492705	2002-12-10	Begley et al			

## Signature

Examiner Name	Date
/Douglas W Owens/	09/06/2006